



PATENT
Customer No. 22,852
Attorney Docket No. 07553.0010

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Saito *et al.*) Group Art Unit: 1763
Application No.: 09/686,370) Examiner: R. Kackar
Filed: October 12, 2000)
For: Processing Apparatus for)
Conservation of Processing Gases)
(As Amended)

Commissioner for Patents
Washington, DC 20231

Sir:

AMENDMENT

In reply to the Office Action dated October 16, 2002, please amend the application as follows:

IN THE CLAIMS:

Please add new claims 16-23.

Please amend claims 1 and 15 as follows:

1. (Three Times Amended) A processing apparatus comprising:
- C1 a gas supply mechanism that supplies a processing gas into a processing chamber via a plurality of gas supply holes including a plurality of primary gas supply holes and a plurality of circulating gas supply holes,
- an evacuating mechanism that evacuates the processing gas from said processing chamber, and

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